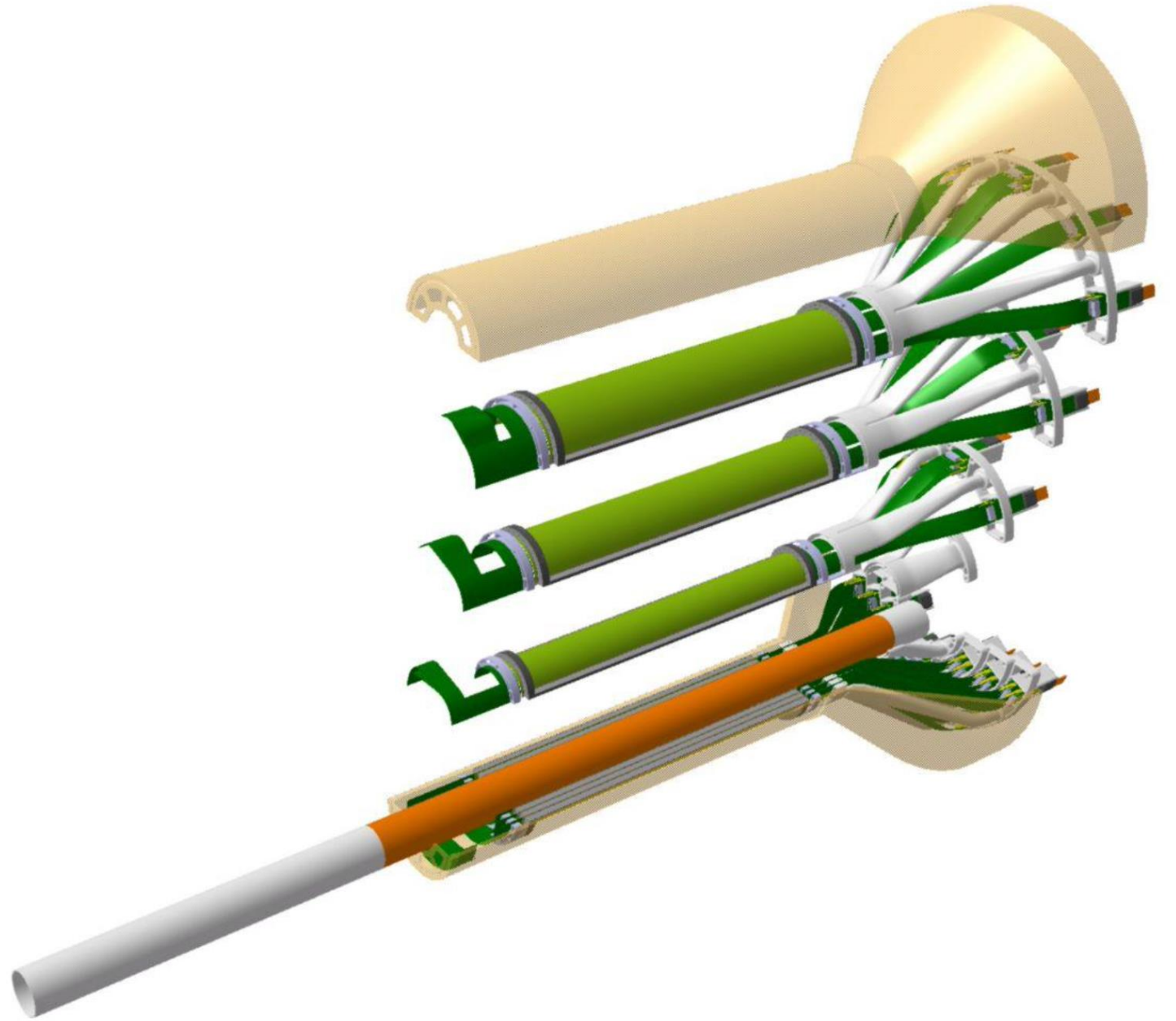


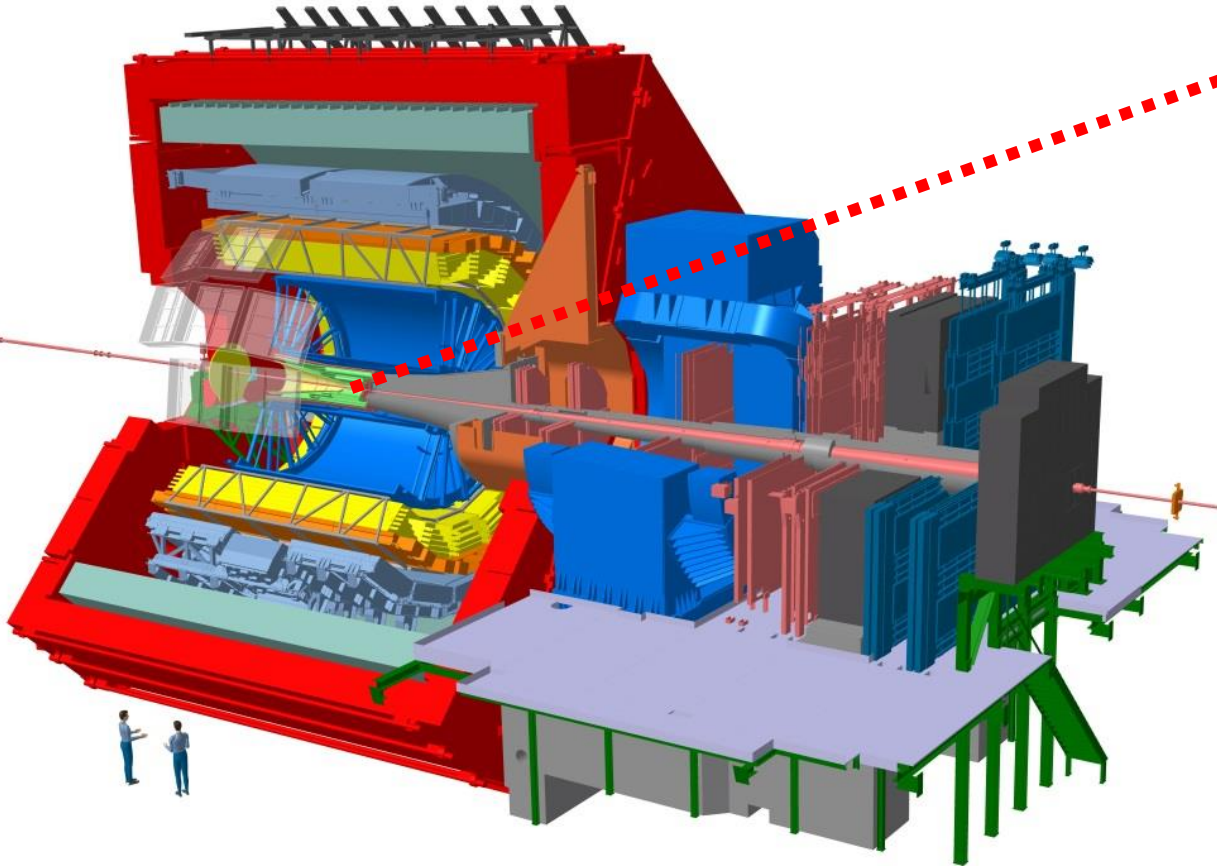


ALICE ITS 3

Serhiy Senyukov (IPHC Strasbourg)
on behalf of ALICE collaboration



ALICE and ITS(s)

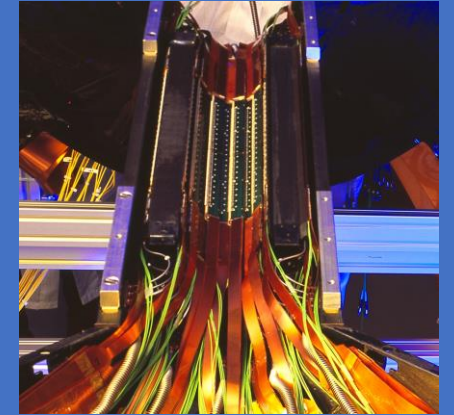


General purpose detector at LHC:

- Tracking (100 MeV/c – 100 GeV/c)
- Particle identification: π , K, p, e (0.1 – 50 GeV/c)

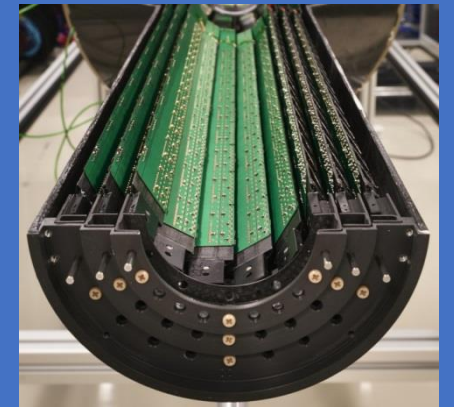
ITS 1 (LHC Run 1/2)

- Hybrid pixels
- Pixels: $50 \times 425 \mu\text{m}^2$
- C4F10 cooling
- $\sim 1.1 \% X_0$



ITS 2 (LHC Run 3)

- MAPS
- Pixels: $27 \times 29 \mu\text{m}^2$
- Water cooling
- $\sim 0.3 \% X_0$ (inner layers)



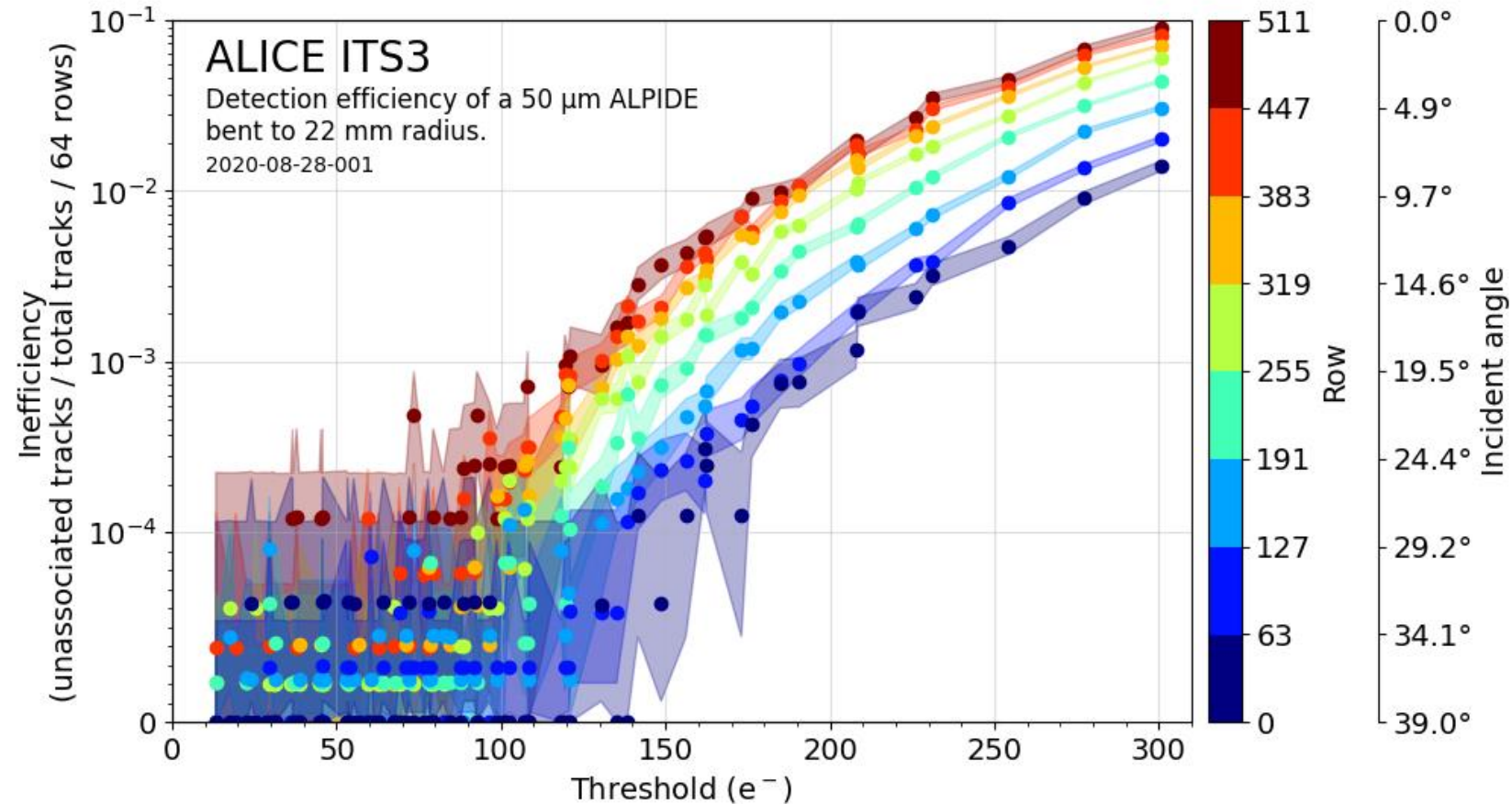
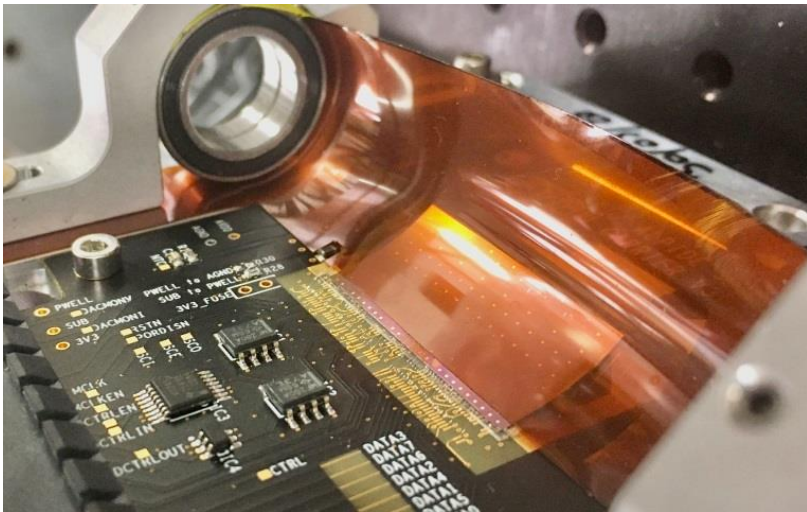
ITS 3 (LHC Run 4)

- Stitched MAPS
- Pixels: $\sim 20 \times 22.5 \mu\text{m}^2$
- Air cooling
- $\sim 0.05 \% X_0$ (inner layers)



Excellent performance for small bent sensors

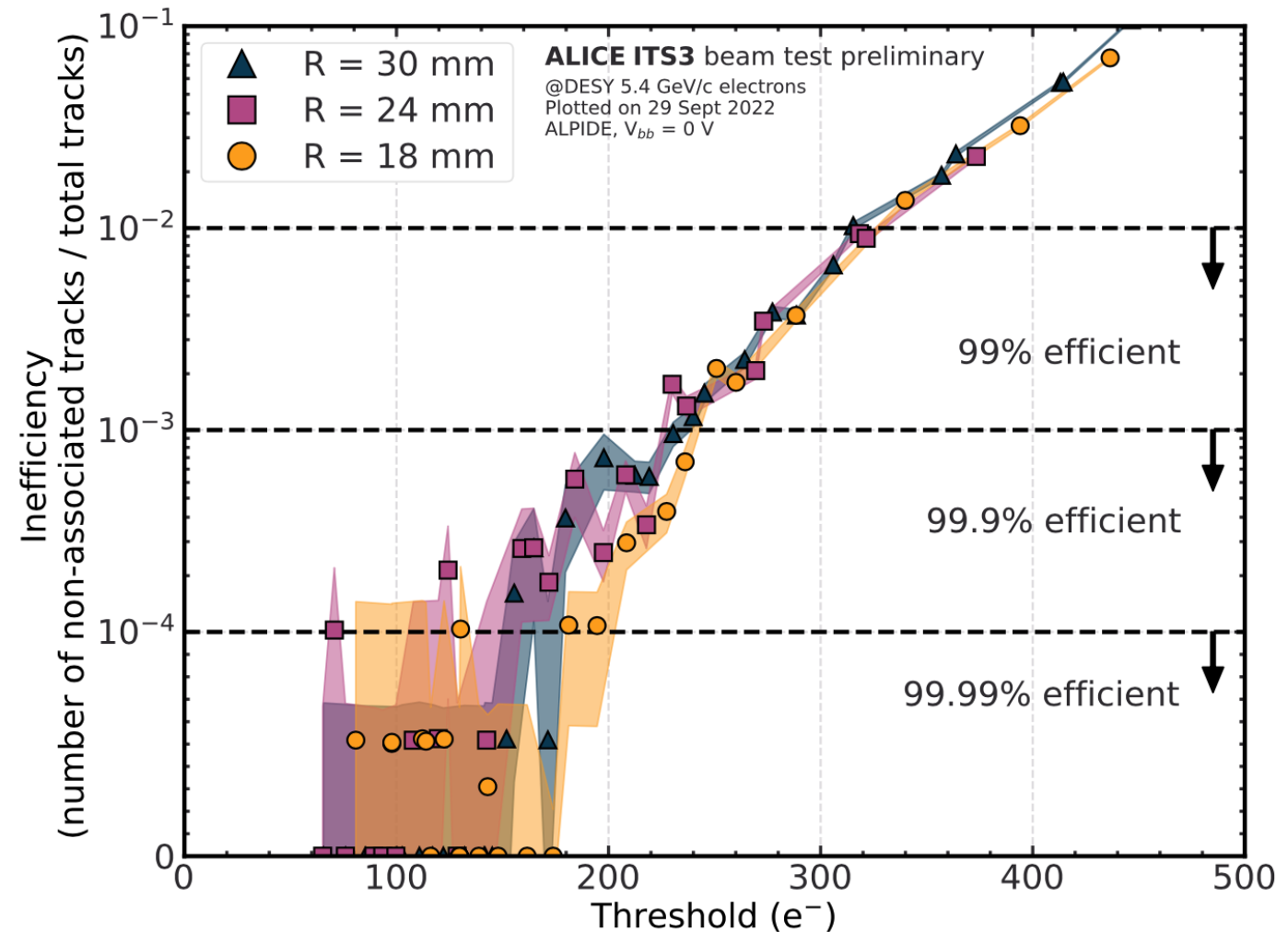
In 2020 50 μm thick ALPIDE chip bent to 22 mm along columns showed excellent efficiency in the beam test



<https://doi.org/10.1016/j.nima.2021.166280>

Excellent performance for small bent sensors

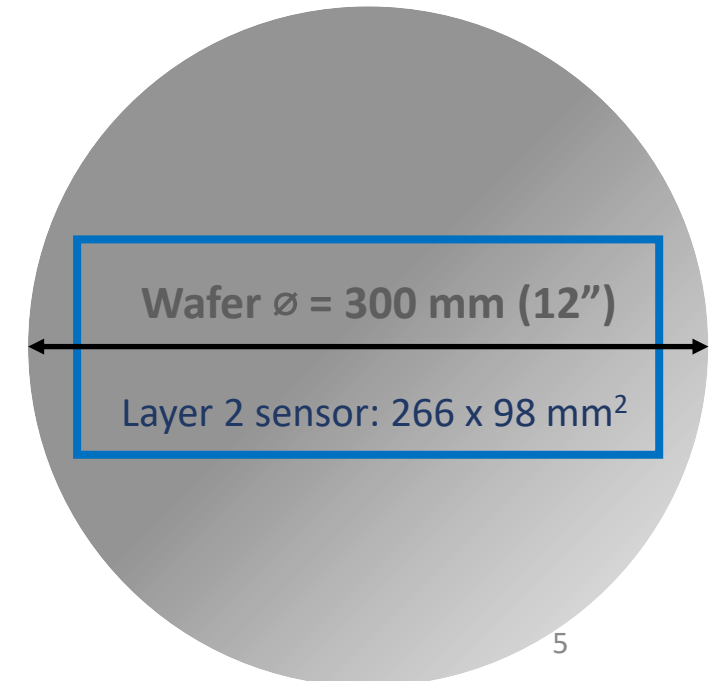
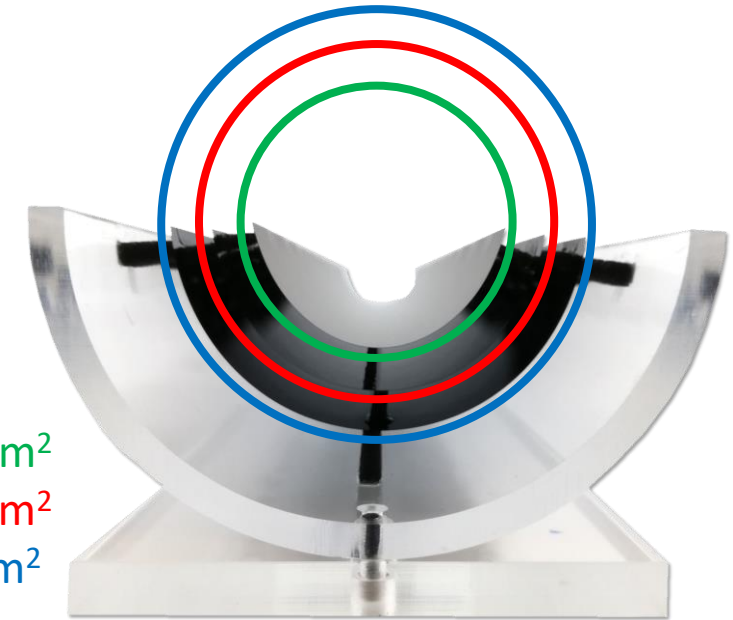
In 2021 μ ITS3 – assembly of 3 ALPIDE sensors bent to ITS3 radii (18, 24, 30 mm) along rows – tested and also showed excellent detection efficiency not depending on the radius



ITS3 requires large sensors → New CMOS process is needed

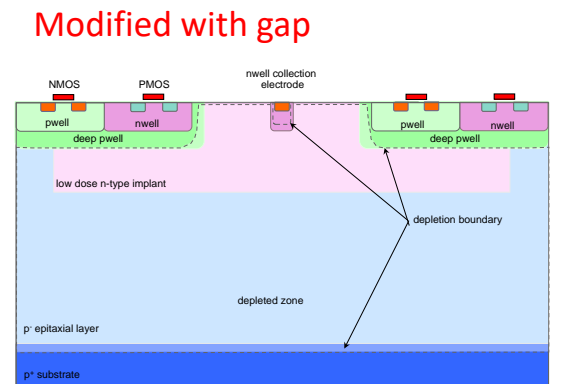
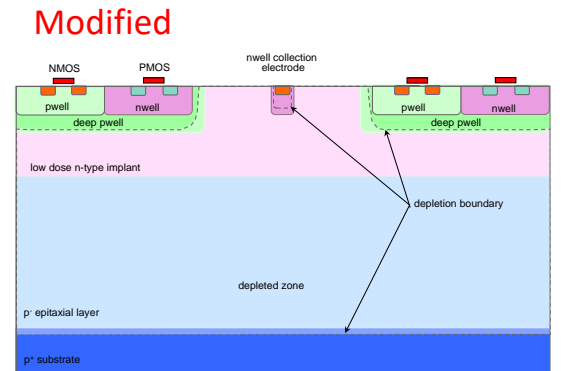
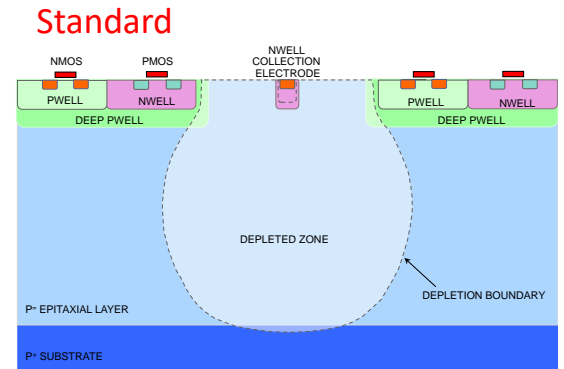
- ITS3 sensors size up to $\sim 27 \times 9 \text{ cm}^2$
- Can only be produced via stitching on 12-inch wafers
- Available from Tower Partners Semiconductor Co. TPSCo in 65 nm
 - Continuation of TJ 180 nm used in ITS2
 - Custom process modifications for full depletion ported from TJ180
 - Lower power consumption
 - Potentially better radiation hardness

2 x 266×59 mm²
2 x 266×79 mm²
2x 266×98 mm²

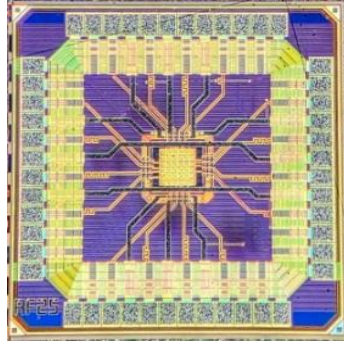


MLR1: first TPSCo 65 nm submission for technology validation

- Submitted Dec 2020 -> Delivered July 2021
- Three main goals:
 - Learn technological features
 - Characterize charge collection
 - Validate radiation hardness
- Large variety of small chips (1.5×1.5 mm²)
 - Analogue and digital blocks
 - 3 pixel matrices: APTS, CE65 and DPTS
- Standard process + 2 modified for better depletion:
 - “Modified” – low dose n-type blanket
 - “Modified with gap” – same as above with gaps on pixel edge



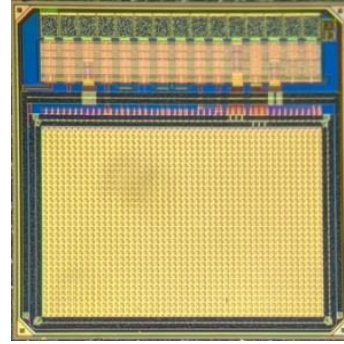
Pixel chips: APTS, CE65, DPTS



APTS

(Analogue Pixel Test Structure)

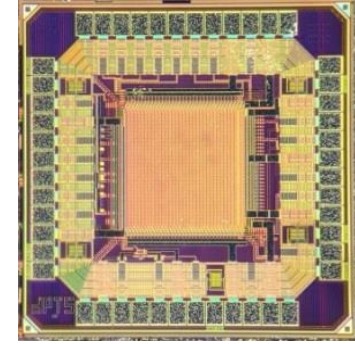
- 6×6 pixel matrix
- Direct analogue readout of central 4×4 submatrix
- Two types of output drivers:
 - Source follower (APTS-SF)
 - Very fast OpAmp (APTS-OA)
- AC/DC coupling
- 4 pitches: 10, 15, 20, 25 μm
- 3 process variations



CE65

(Circuit Exploratoire 65 nm)

- 2 matrix sizes
 - 64×32 with 15 μm pitch
 - 48×32 matrix with 25 μm pitch
- Rolling shutter readout (50 μs integration time)
- 3 in-pixel architectures:
 - AC-coupled amplifier
 - DC-coupled amplifier
 - Source follower
- 4 chip variants:
 - **Standard process 15 μm pitch**
 - Modified process 15 μm pitch
 - **Modified process with gaps 15 μm pitch**
 - Standard process 25 μm pitch



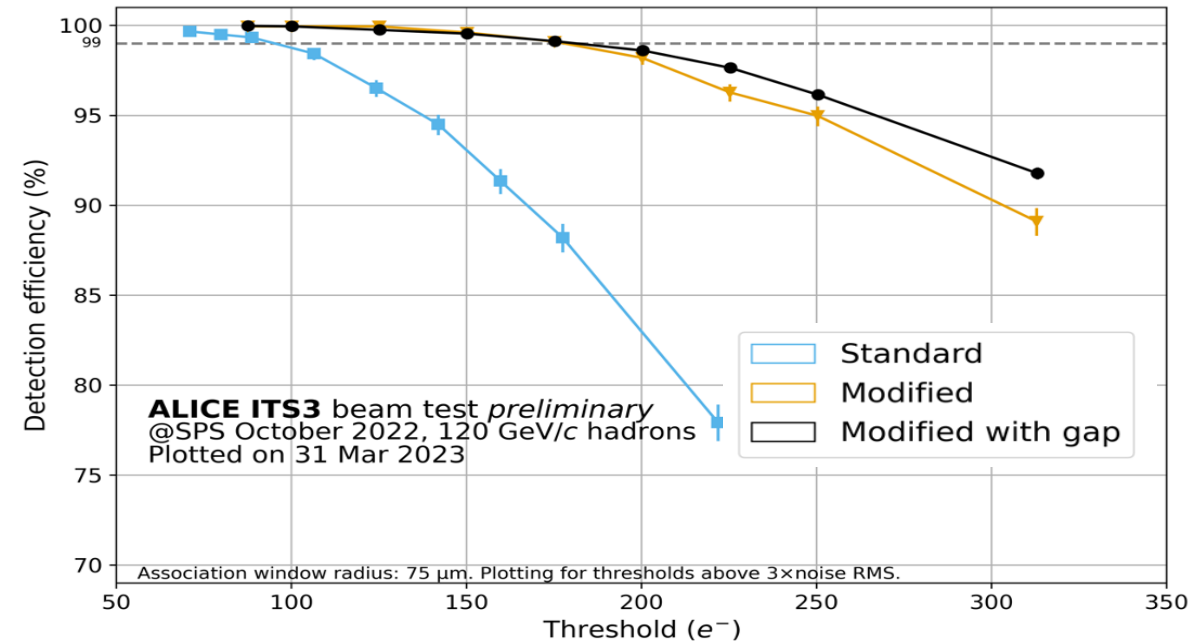
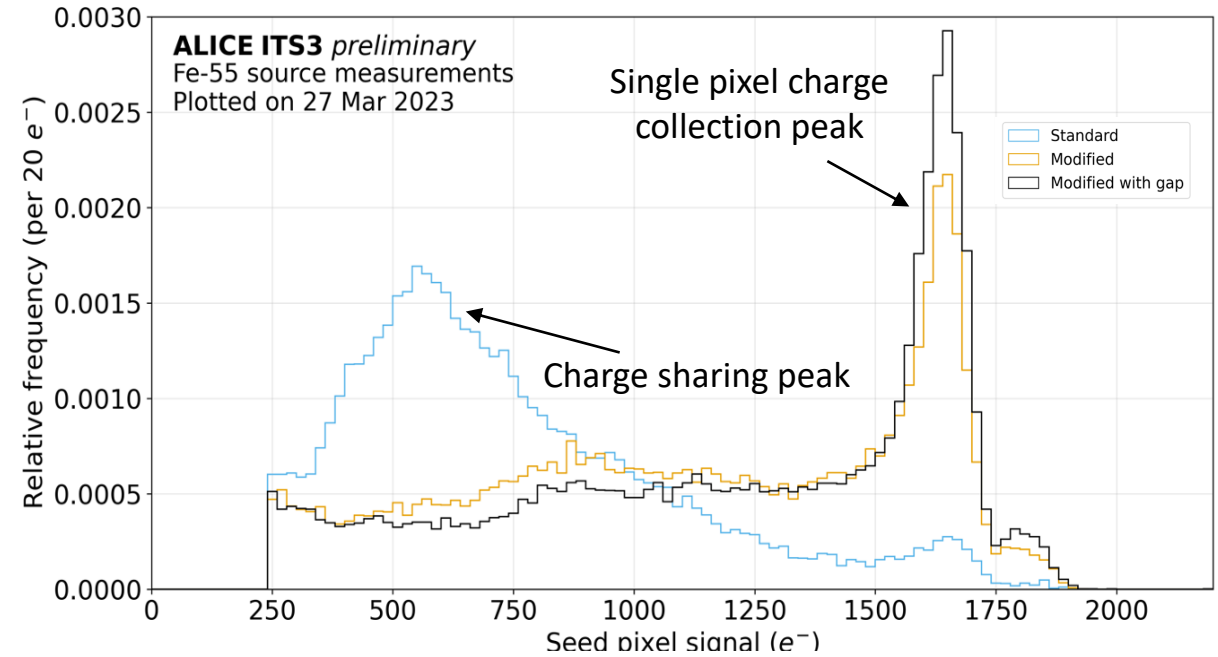
DPTS

(Digital Pixel Test Structure)

- 32×32 pixel matrix
- Asynchronous digital readout
- Time-over-Threshold information
- Pitch: 15×15 μm^2
- Only “modified with gap” process modification

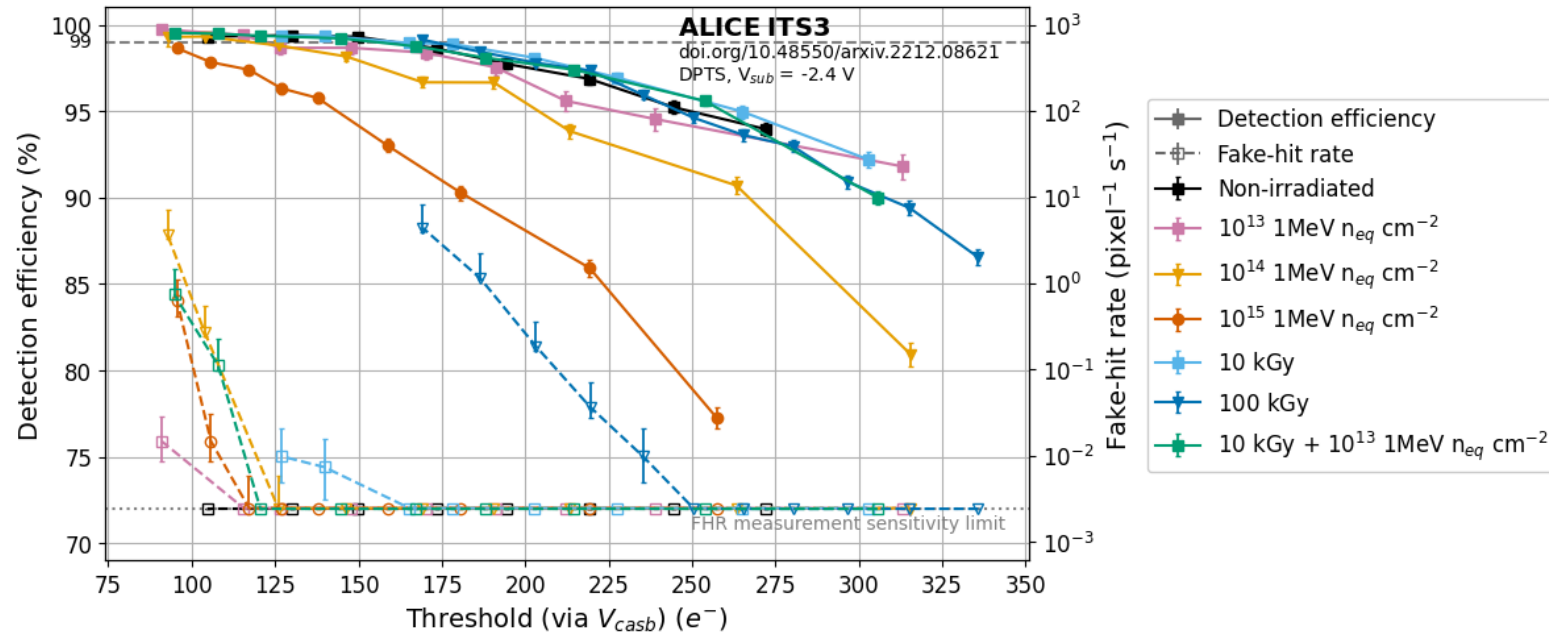
Characterization results: effect of modified process

- Process modifications make almost all the charge to be collected by seed pixel due to full depletion of epi-layer
- This effect greatly extends working range with excellent detection efficiency



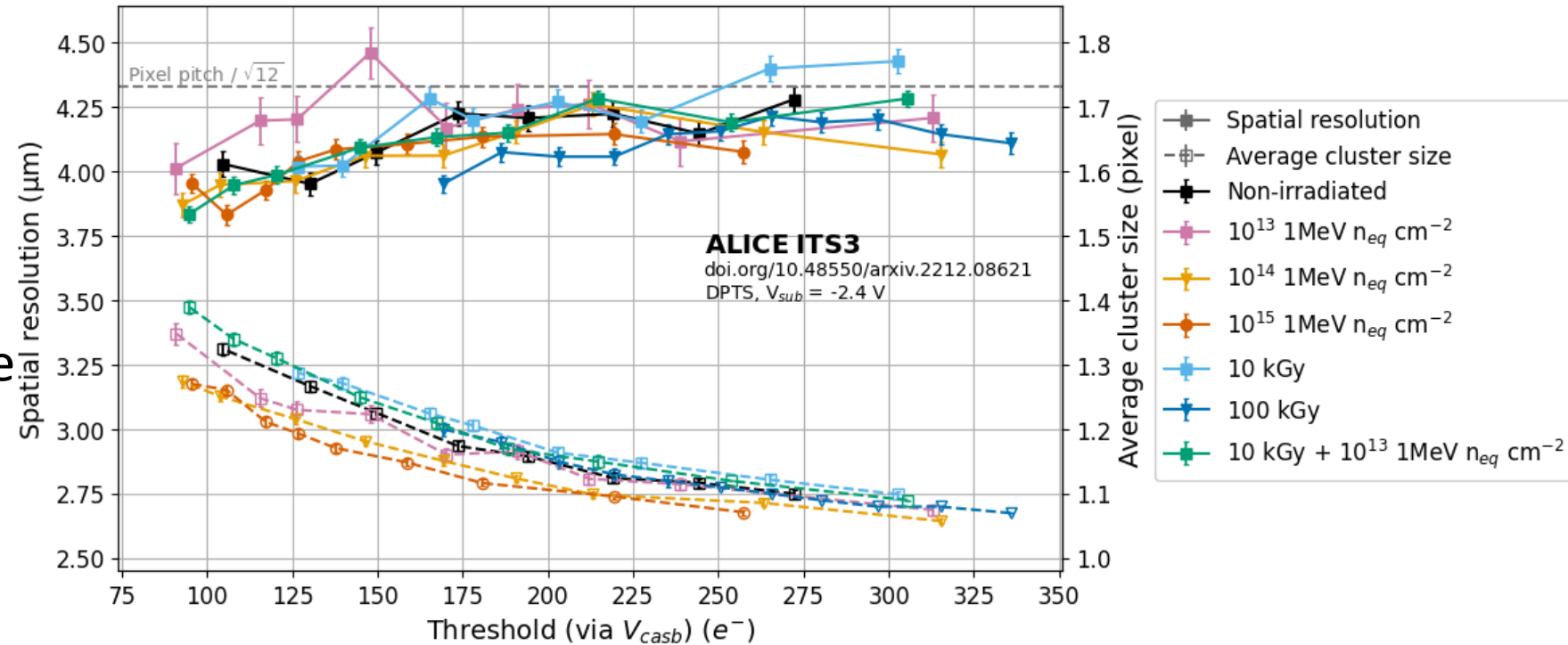
Detection efficiency and FHR vs. irradiation

- Detection efficiency decreases with NIEL dose
- FHR increases with TID dose
- **Perfect performance at ITS3 combined level of 10 kGy + $10^{13} n_{eq}/cm^2$**



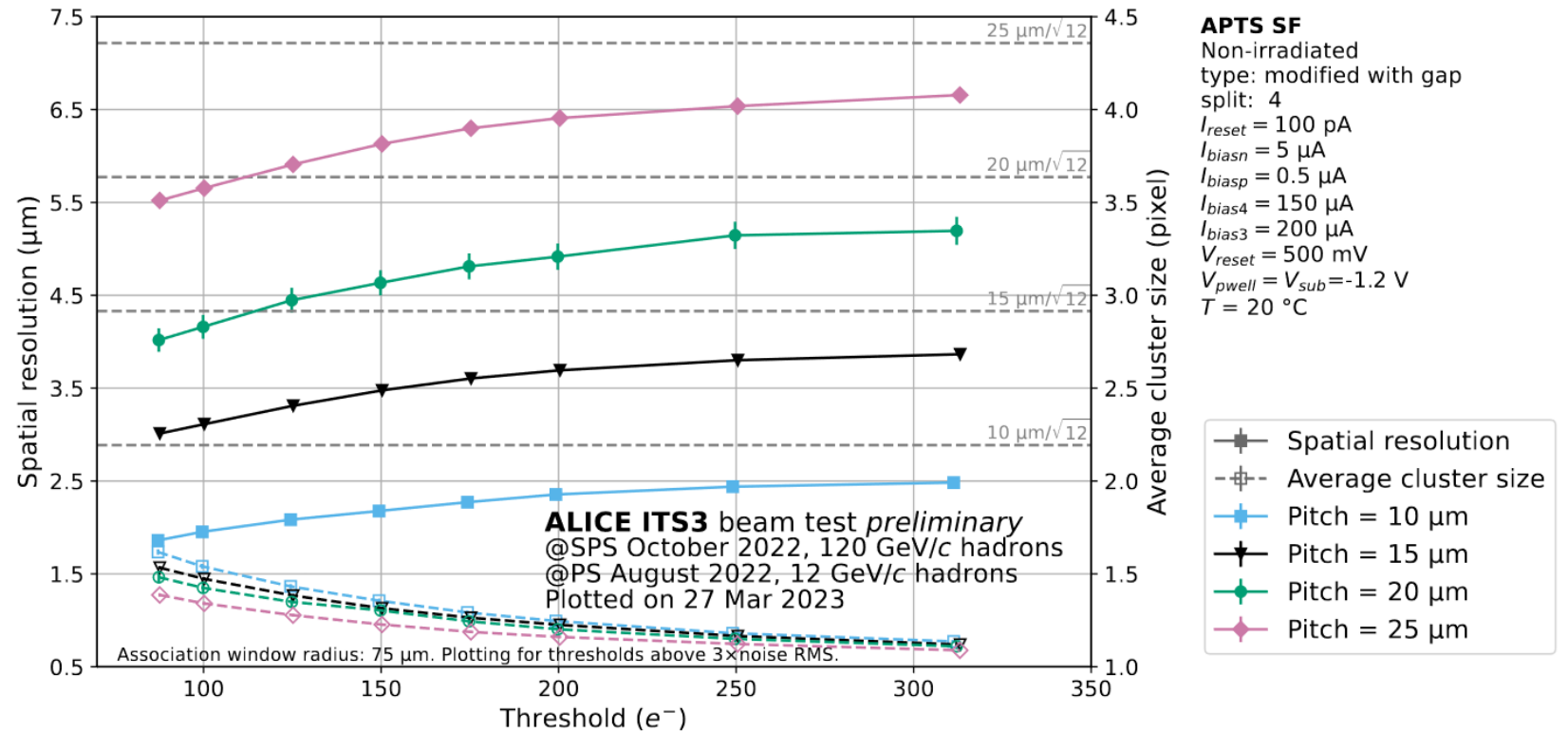
Spatial resolution and cluster size vs. irradiation

- Spatial resolution isn't affected by irradiation
- Cluster size slightly increases with NIEL irradiation
- Resolution is compatible with mostly single pixel clusters and digital readout

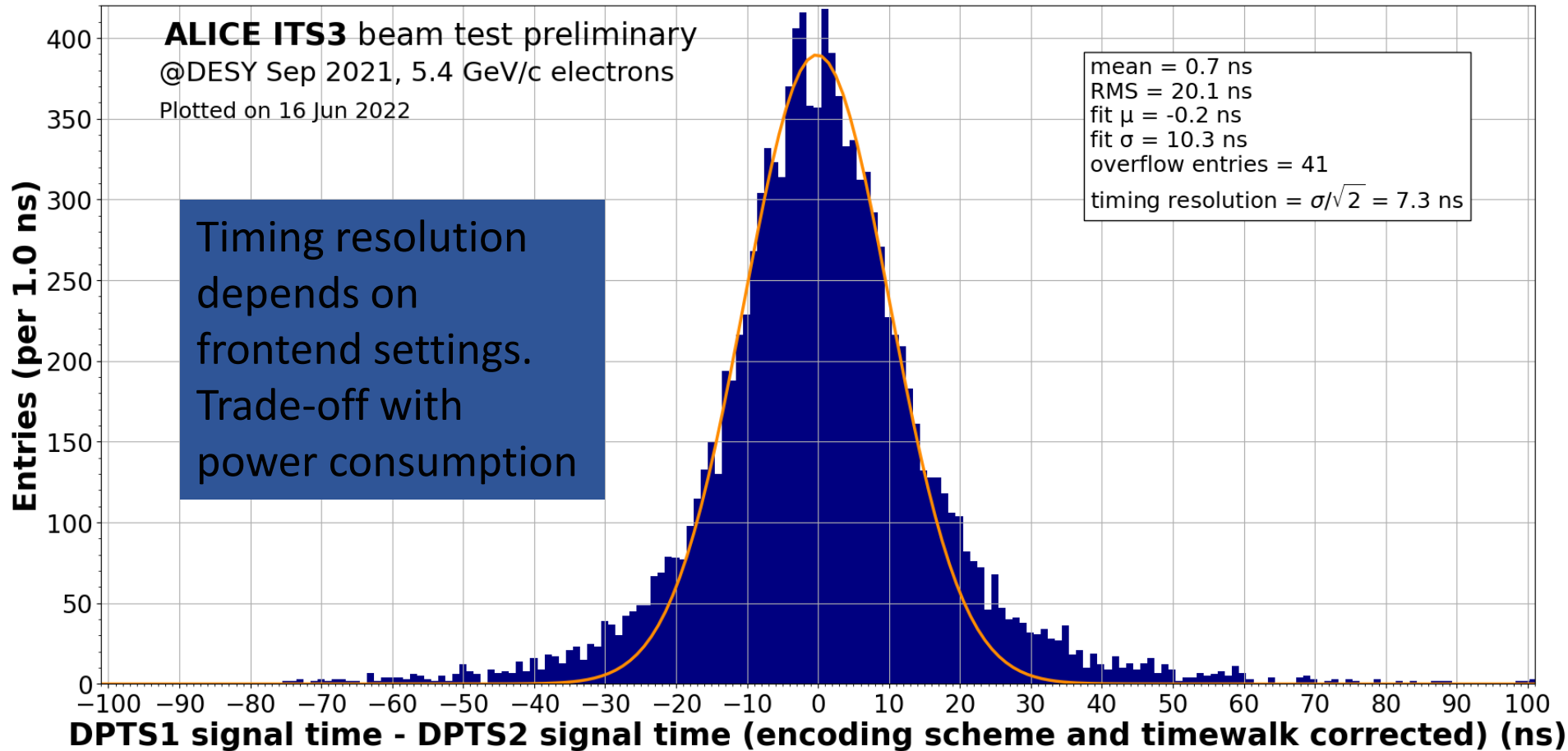


Spatial resolution and cluster size vs. pitch

- Weak dependence of cluster size on pixel pitch
- **Spatial resolution of about 5 μm for expected pitch value of 22 μm**



DPTS: Temporal resolution ~ 7 ns



DPTSOW22B3 (not irradiated)

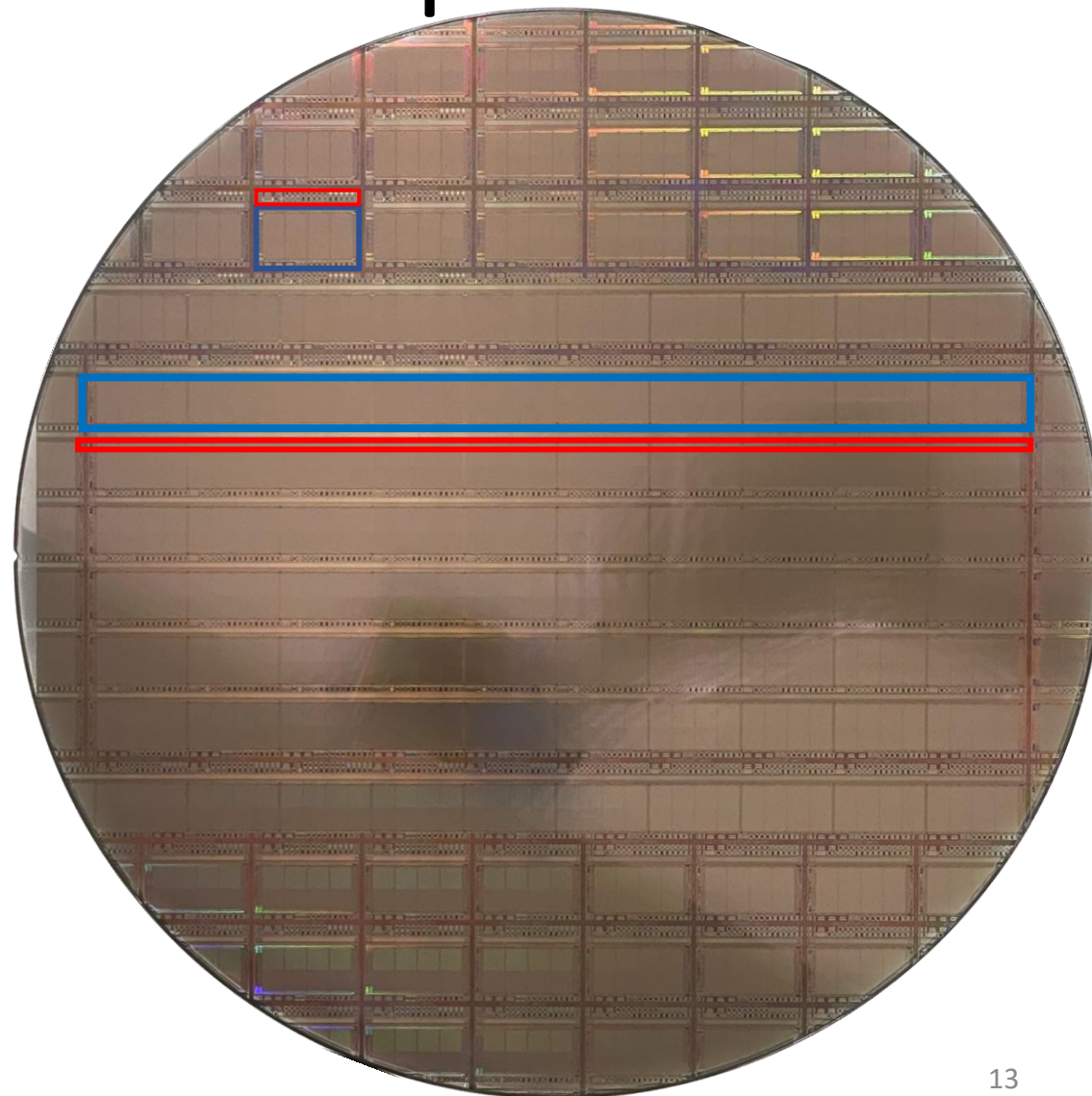
version: 0
split: 4 (opt.)
 $I_{reset} = 10$ pA
 $I_{bias} = 100$ nA
 $I_{biasn} = 10$ nA
 $I_{db} = 100$ nA
 $V_{casn} = 300$ mV
 $V_{casb} = 250$ mV
 $V_{pwell} = V_{sub} = -1.2$ V

DPTSXW22B1 (not irradiated)

version: X
split: 4 (opt.)
 $I_{reset} = 10$ pA
 $I_{bias} = 100$ nA
 $I_{biasn} = 10$ nA
 $I_{db} = 100$ nA
 $V_{casn} = 300$ mV
 $V_{casb} = 280$ mV
 $V_{pwell} = V_{sub} = -1.2$ V

ER1: First submission of stitched chips

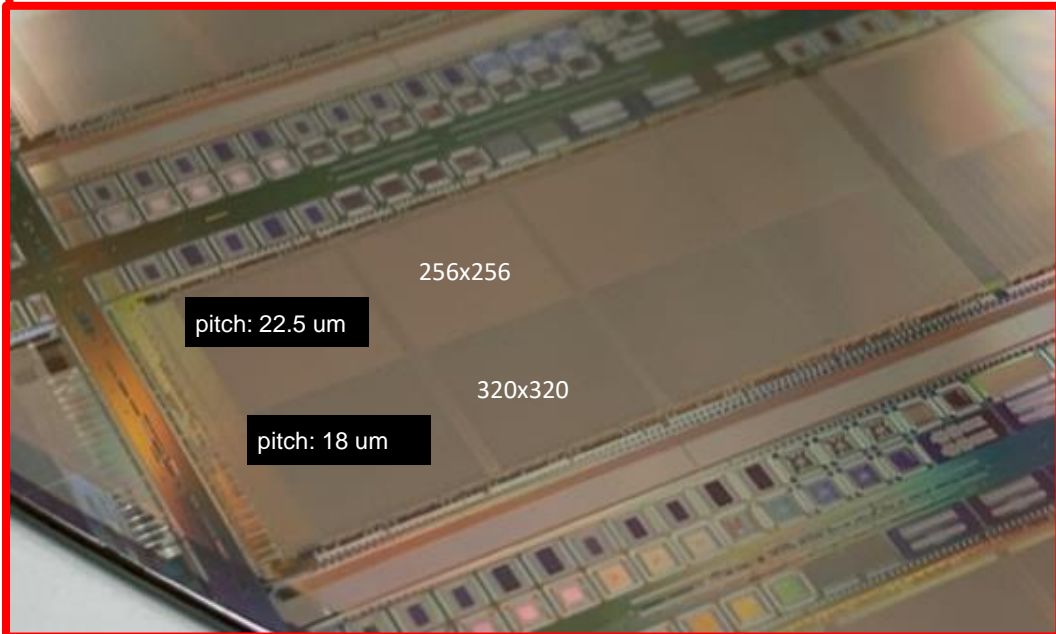
- Submitted Dec 2022
- Received May 2023
- Two types of stitched chips:
 - MOSS (259×14 mm²)
 - MOST (259×2.5 mm²)
- 1/10 versions of MOSS(T)
 - Baby-MOSS
 - Baby-MOST
- Multiple small chips (1.5×1.5 mm²)



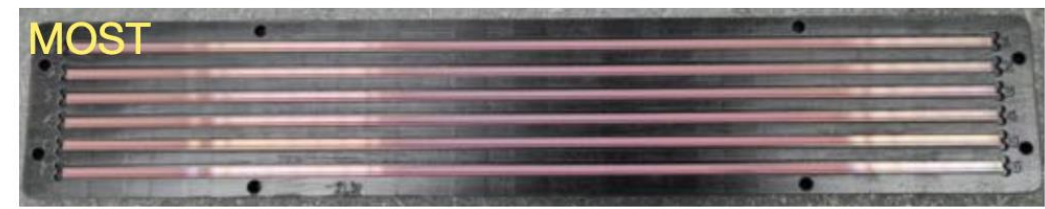
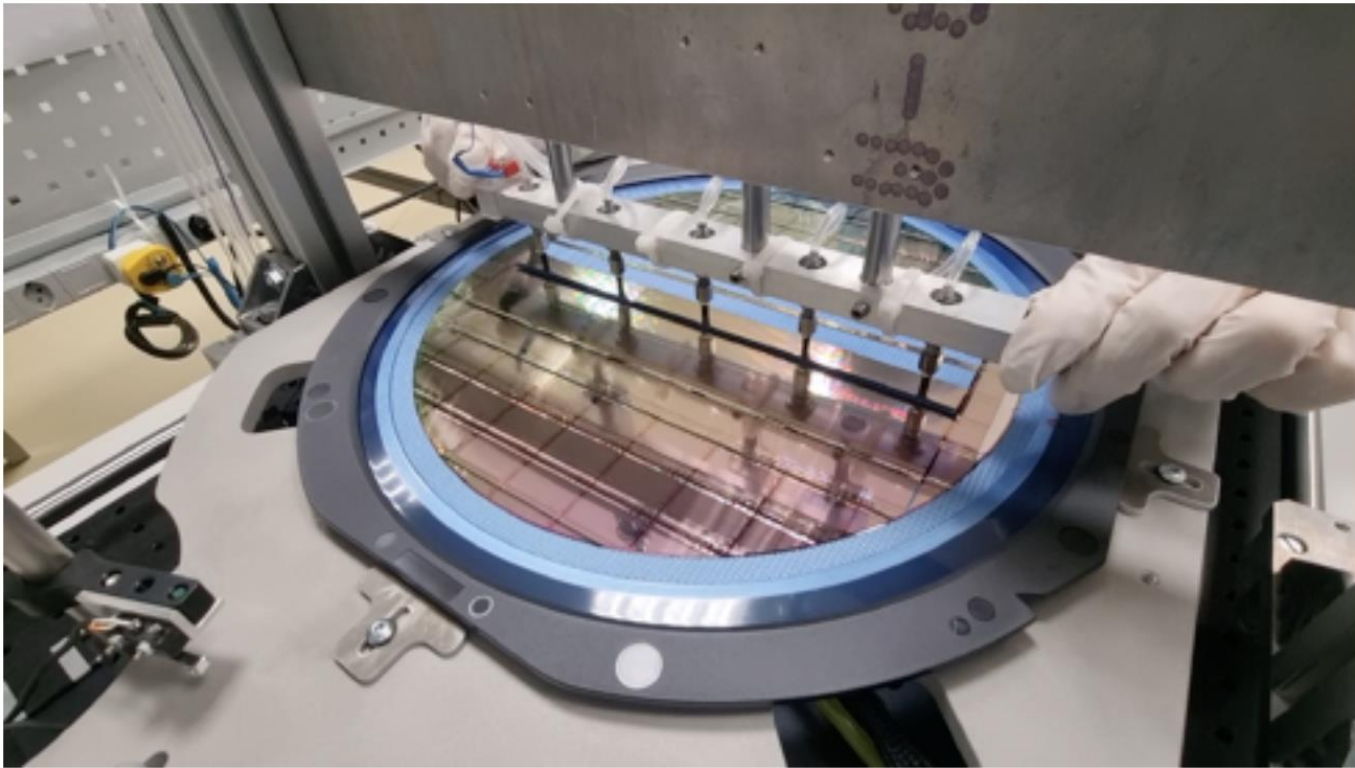
MOSS - MOnolithic Stitched Sensor



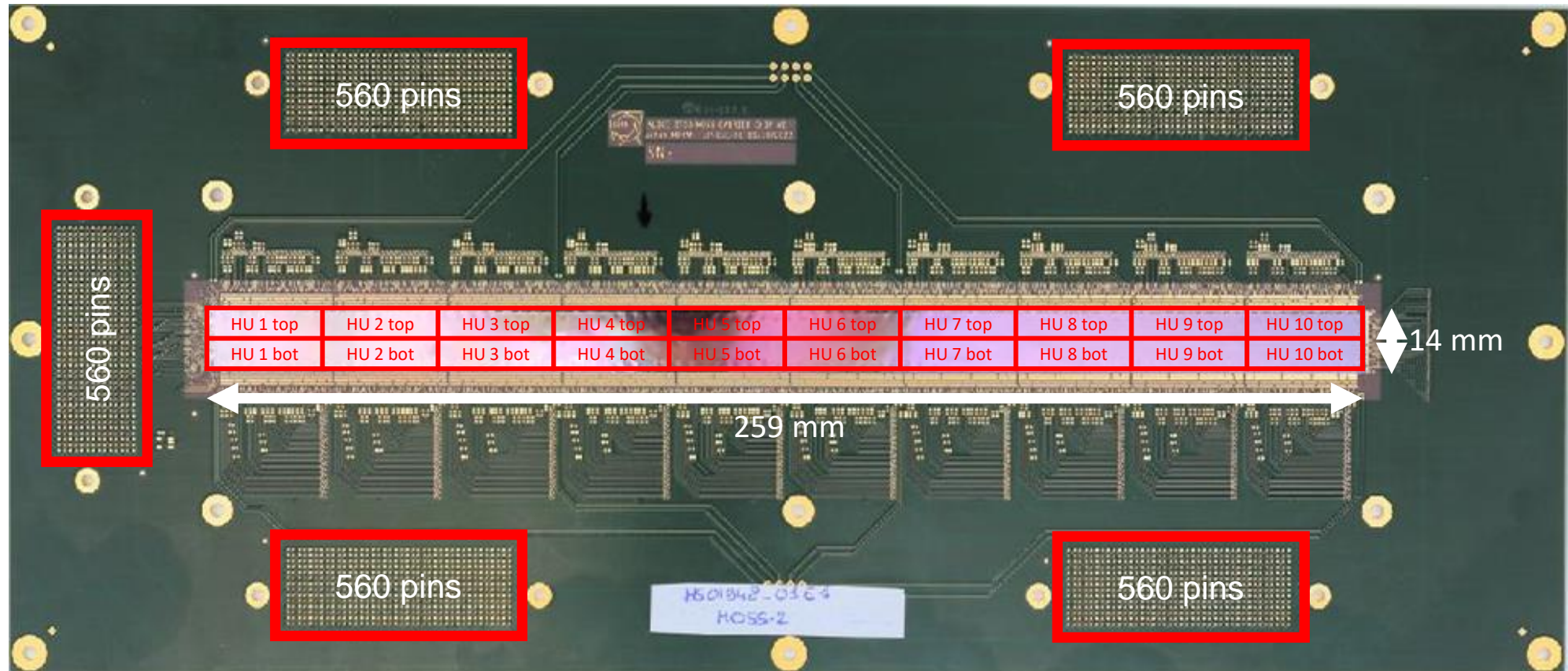
- **10 Repeated Sensor Units (RSUs)** per sensor
 - Independent power supply, control & readout
 - **2 half-units (HUs)** per RSU
 - Power segmentation domains
 - **Top (22.5 um pitch):**
 - Conservative layout
 - 7 mW/cm² (analog FE)
 - **Bottom (18 um pixel pitch):**
 - Compact layout
 - 11 mW/cm² (analog FE)
 - **4 regions** in each half-unit



Challenging handling of stitched chips



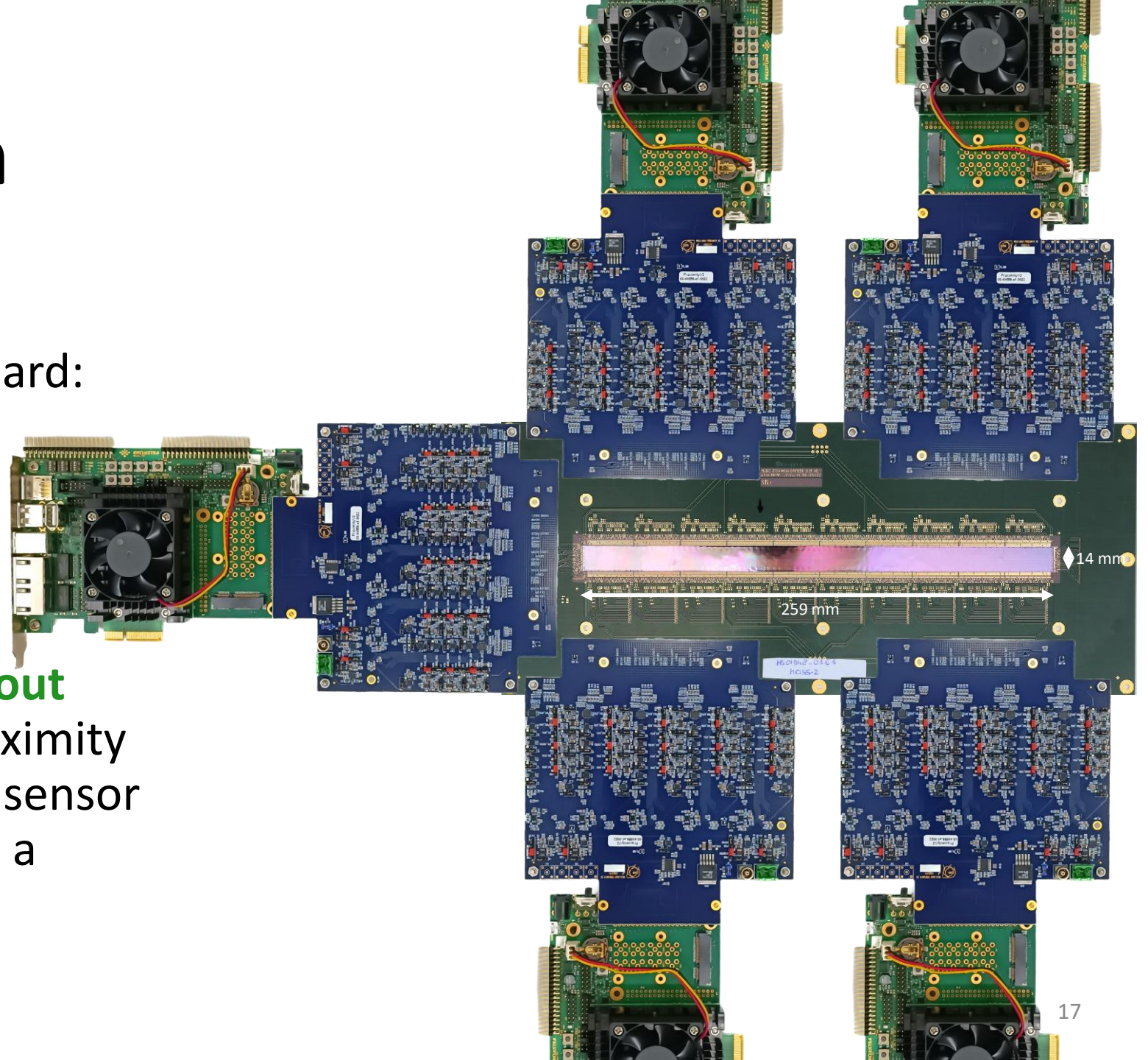
MOSS on the carrier card



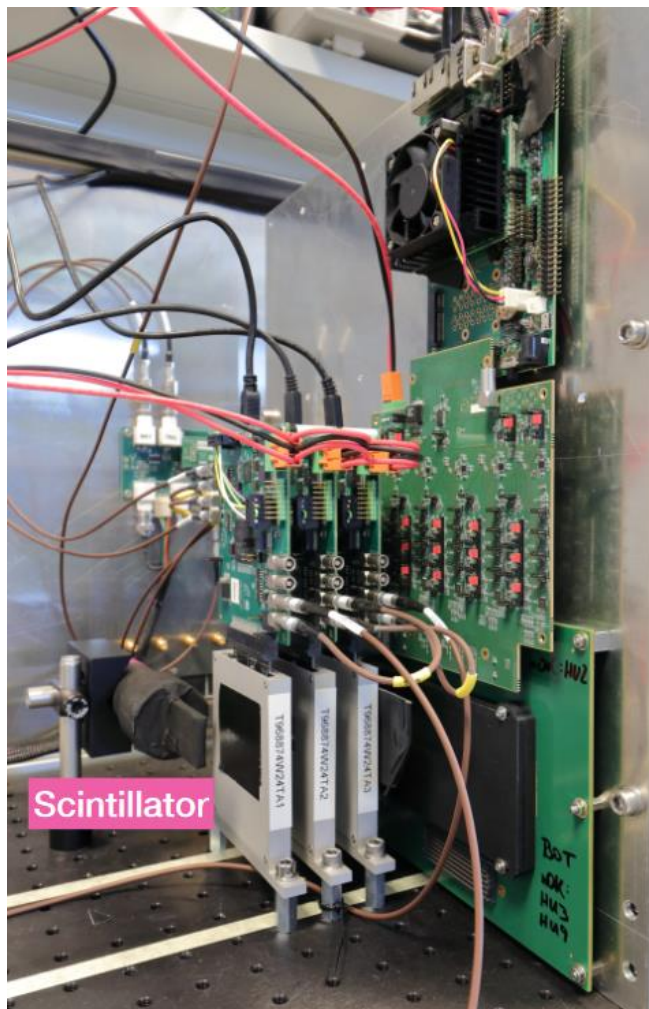
MOSS test system

Three different types of board:

- **Carrier card**
- **5x proximity cards**
 - 1 card x 4 quadrants
 - 1 top/bottom halves
- **5x automation and readout modules** to steer the proximity boards and interface the sensor control and readout with a computer

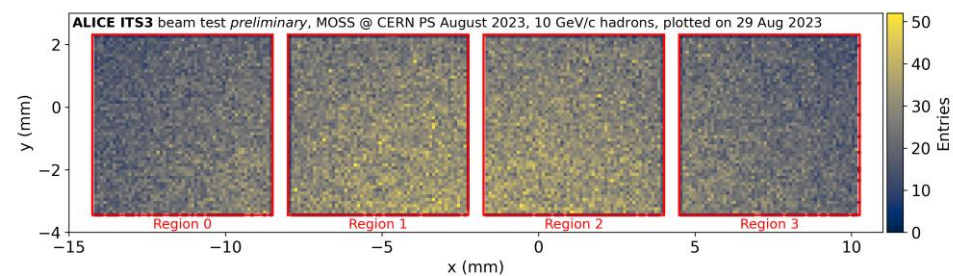
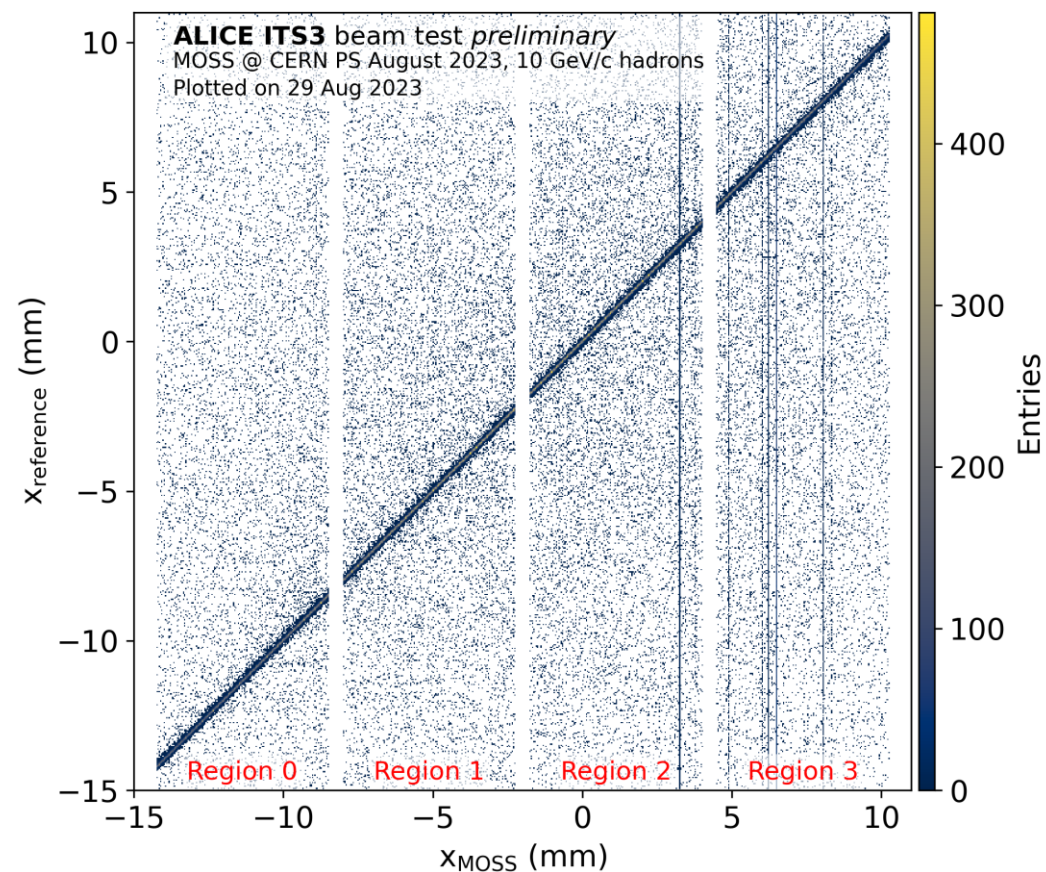


MOSS – first test results



- 16 MOSS bonded and being tested
- Collecting data on the yield
- First chips tested with the beam

20-09-2023



18

Summary and outlook

- Bending of MAPS down to 18 mm doesn't affect their performance
- TPSCo 65 nm CMOS process is validated for ITS3:
 - Spatial resolution: $\sim 5 \mu\text{m}$
 - Radiation hardness: $10 \text{ kGy} + 10^{13} n_{\text{eq}}/\text{cm}^2$
- First stitched prototypes work and being tested
- ER2 submission in preparation: final full scale sensor prototype
- TDR to be presented to LHCC in November 2023



ALICE